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PATENT
Attorney Docket No.: A7188/T47800
Client Ref. No.: AMAT No.
007188/DISPLAY/AKT/BG

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Sheng Sun et al.

Application No.: 10/817,611

Filed: April 2, 2004

For: METHOD AND SYSTEM FOR
CONTROL OF PROCESSING
CONDITIONS IN PLASMA
PROCESSING SYSTEMS

Customer No.: 57385

Confirmation No. 2449

Examiner: Joel G. Horning

Technology Center/Art Unit: 1792

AMENDMENT

Mail Stop AF
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Commissioner:

In response to the final Office Action mailed November 4, 2009, please enter the following amendments and remarks:

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks begin on page 7 of this paper.